

## LAM Research TCP9600 Metal Etch 200mm Configuration SN 42264

Information contained in this presentation is confidential









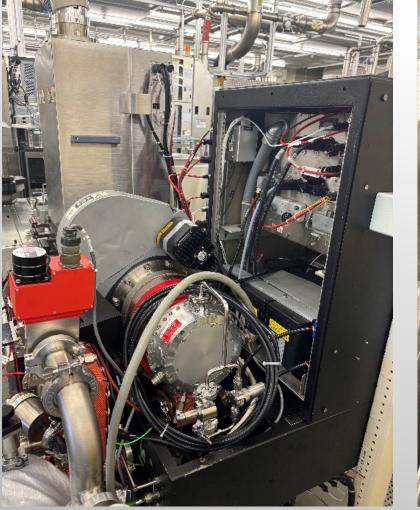
**Currently Configured for 200mm Wafers** Install Type: Stand-Alone/Ballroom SMIF System SW: Envision 1.6.1-012 Vintage 1999 **ASYST SMIF Send/Receive indexers** Mainframe: TCP9600SE CFE **WVDS On-Board AC Dist. On-Board RF Generators:** (3) Onboard AE RFG 1250 **SECS** Interface Main Process Module (PM1): TCP 9600SE Wafer Clamp: ESC w/He Cooling Electrode Gap: Fixed gap 8" TCP Coil Turbo CNTRI: BOC Edwards 1300 Gate Valve: VAT 65 (heated) Heated Pump Stack & Manifold **Endpoint Detection: Dual Photo diode** Endpoint Wavelength(s): 703nm and 261.8nm PM2: DSQ Stripper Hinged DSQ

Gas Box Config: **Orbitally Welded Gas Box Backside Helium Cooling** Gas Line 1245678 Gas Flow (sccm) MFC Mfgr. MFC Model Cl2 100 Unit 1660 BCL3 100 Unit 1660 CH4 10 Unit 1660 10 Unit 1660 N2 02 200 Unit 1660 02 500 Unit 1660 500 Tylan VC-4900VRH H20 Power Requirements: 208V, 80A, 3-Phase, Freq 50/60Hz

#### Missing items;

Chamber Manometer 0.1 torr Watertank WVDS unhooked but with machine











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